

Optimising CMOS Pixel Sensors for the ILC Micro-Vertex Detector

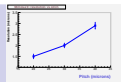
Marc Winter (IPHC/Strasbourg)

on behalf of DAPNIA/Saclay, LPSC/Grenoble, LPC/Clermont-F., DESY, Uni. Hamburg & IPHC/Strasbourg
contributions from IPN/Lyon, Uni. Frankfurt, GSI-Darmstadt, STAR coll.(LBNL, BNL), JINR-Dubna

▶ More information on IPHC Web site: http://wwwires.in2p3.fr/ires/web2/rubrique.php3?id_rubrique=63

OUTLINE

- **Reminder on CMOS sensors:** ⇄ *Specific advantages* ⇄ *Specific limitations*
- **Achieved performances with analog output sensors (AMS-0.35 OPTO fab. process) :**
 - ⇄ *Detection efficiency* ⇄ *Spatial resolution* ⇄ *Operating temperature* ⇄ *Radiation tolerance*
 - ⇄ *Thinning* ⇄ *Ladder design* ⇄ *Current applications (telescopes)*
- **Fast read-out architecture:** ⇄ *State of the art* ⇄ *Plans until 2009/10*
- **Summary – Outlook**



p-type low-resistivity Si hosting n-type "charge collectors"

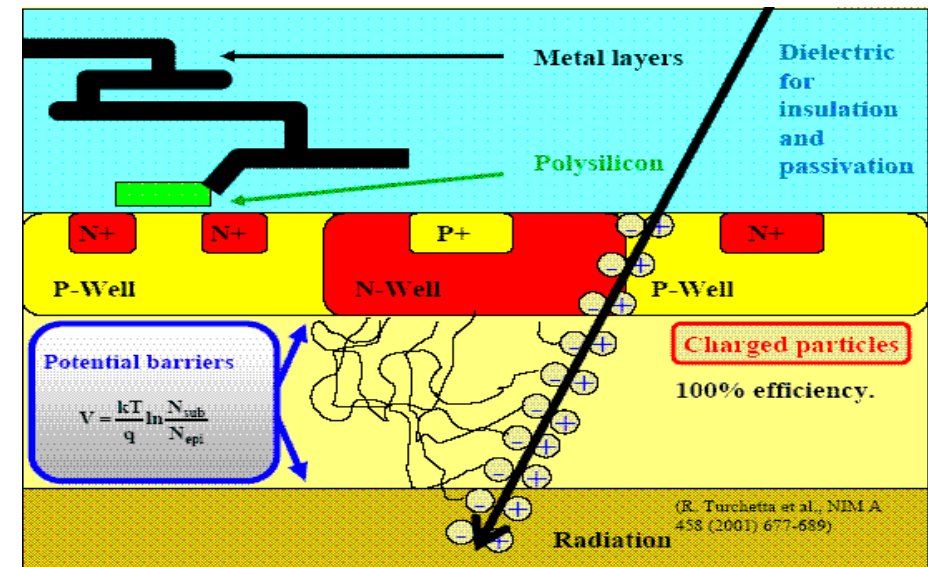
- signal created in epitaxial layer (low doping):
 $Q \sim 80 \text{ e-h} / \mu\text{m} \mapsto \text{signal} \lesssim 1000 \text{ e}^-$
- charge sensing through n-well/p-epi junction
- excess carriers propagate (thermally) to diode with help of reflection on boundaries with p-well and substrate (high doping)

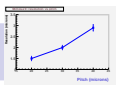
Specific advantages of CMOS sensors:

- ◇ Signal processing μ circuits integrated on sensor substrate (system-on-chip) \mapsto compact, flexible
- ◇ Sensitive volume (\sim epitaxial layer) is $\sim 10\text{--}15 \mu\text{m}$ thick \longrightarrow thinning to $\sim 30\text{--}40 \mu\text{m}$ permitted
- ◇ Standard, massive production, fabrication technology \longrightarrow cheap, fast turn-over
- ◇ Room temperature operation
- ◇ Attractive balance between granularity, mat. budget, rad. tolerance, r.o. speed and power dissipation

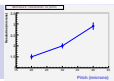
■ BUT : ❌ Very thin sensitive volume \mapsto impact on signal magnitude (mV !)

- ❌ Sensitive volume almost undepleted \mapsto impact on radiation tolerance & speed
- ❌ Commercial fabrication (parameters) \mapsto impact on sensing performances & radiation tolerance
- ❌ NWELLS used for charge coll. \mapsto restricted use of PMOS transistors



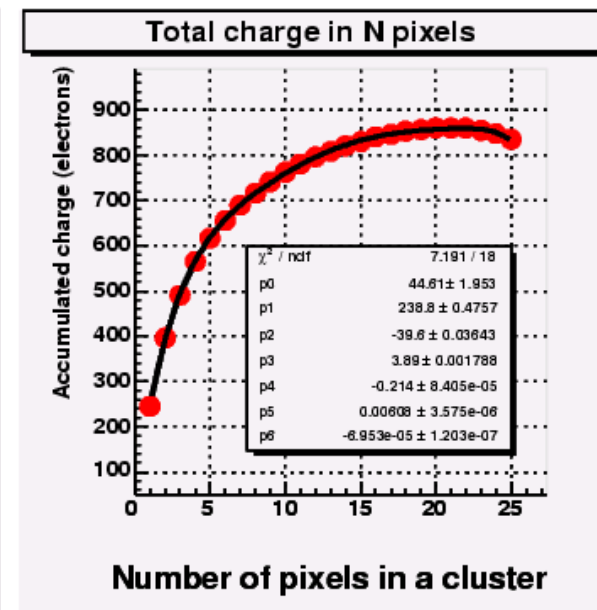
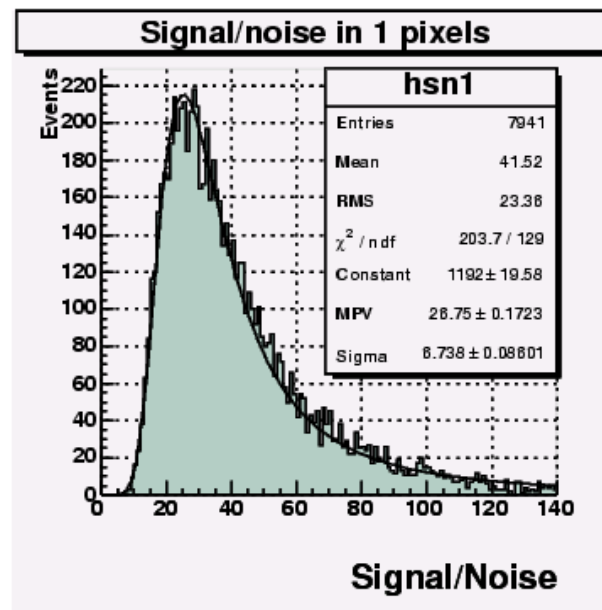
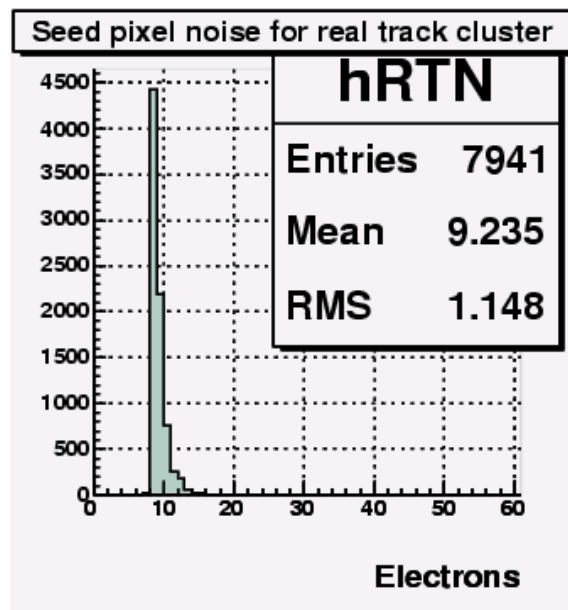


Achieved Performances with Analog Output Sensors

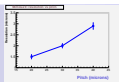


~ 100 chips (M1, M2, M4, **M5**, M8, M9, M11, M14, M15, M16, **M17**, **M18**) tested on H.E. beams since 2001 at CERN-SPS & DESY, mounted on Si-strip telescope (calibrated with ^{55}Fe) \mapsto *well established perfo. (analog output):*

- Best performing technology: AMS 0.35 μm OPTO \mapsto ~ 11 & 15 μm epitaxy (called epi-14 and epi-20)
- $N \sim 10 e^- \text{ ENC} \mapsto S/N \gtrsim 20 - 30$ (MPV) at room Temperature

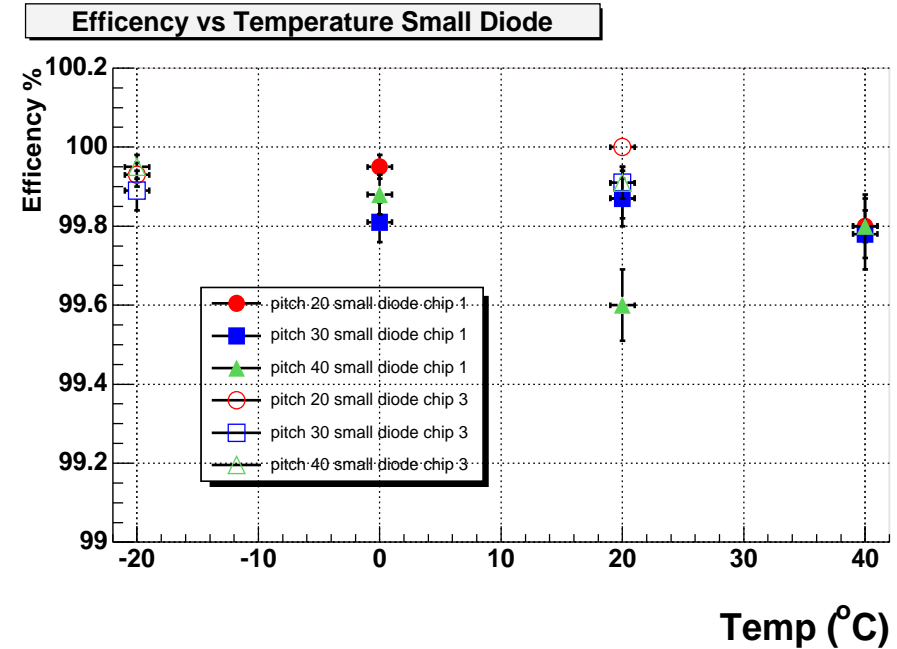


- Technology without epitaxy also performing well : very high S/N but large clusters (hit separation \searrow)
- Macroscopic sensors : MIMOSA-5 ($\sim 1.7 \times 1.7 \text{ cm}^2$; 1 Mpix) ; MIMOSA-20 ($1 \times 2 \text{ cm}^2$; 200 kpix) ; MIMOSA-17 ($0.76 \times 0.76 \text{ cm}^2$; 65 kpix) ; MIMOSA-18 ($0.55 \times 0.55 \text{ cm}^2$; 256 kpix)



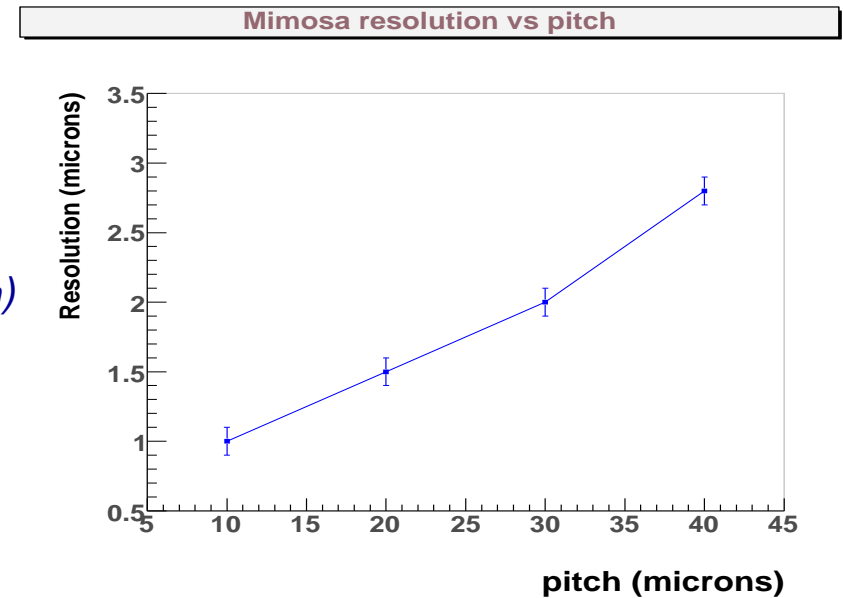
Detection efficiency:

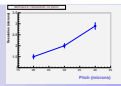
- ⊖ *Ex: MIMOSA-9 data (20, 30 & 40 μm pitch)*
- ⊖ $\epsilon_{det} \gtrsim 99.5\text{--}99.9\%$ repeatedly observed at room temperature (fake rate $\sim 10^{-5}$)
- ⊖ $T_{oper.} \gtrsim 40^\circ\text{C}$



Single point resolution versus pixel pitch:

- ⊖ *clusters reconstructed with eta-function, exploiting charge sharing between pixels (12-bit ADC)*
- ⊖ $\sigma_{sp} \sim 1\ \mu\text{m}$ (10 μm pitch) $\rightarrow \lesssim 3\ \mu\text{m}$ (40 μm pitch)
- ⊖ 4-bit ADC simul. $\Rightarrow \sigma_{sp} \lesssim 2.\ \mu\text{m}$ (20 μm pitch)





Requirements:

- * **beamstrahlung** (GuineaPig X 3) : $\lesssim 10^3 e_{BS}^{\pm}/\text{cm}^2/25 \mu\text{s} \rightsquigarrow \lesssim 2 \cdot 10^{12} e_{BS}^{\pm}/\text{cm}^2/\text{yr}$
 $\hookrightarrow \text{O}(100) \text{ kRad/yr} - \text{O}(10^{11}) n_{eq}/\text{cm}^2/\text{yr}$ (NIEL $\sim 1/30$)
- * **neutron gas**: $\lesssim 10^{10} n_{eq}/\text{cm}^2/\text{yr}$ (MC X 10)

Non-ionising radiation tolerance (20 μm pitch):

- * **MIMOSA-15 irradiated with O(1 MeV) neutrons tested on DESY e^- beams : Preliminary results**

- $T = -20^\circ\text{C}$, $t_{r.o.} \sim 700 \mu\text{s}$
- $5.8 \cdot 10^{12} n_{eq}/\text{cm}^2$ values derived with **standard** and with **soft** cuts

Fluence	0	0.47	2.1	5.8 (5/2)	5.8 (4/2)
S/N (MPV)	27.8 ± 0.5	21.8 ± 0.5	14.7 ± 0.3	$8.7 \pm 2.$	$7.5 \pm 2.$
Det. Eff. (%)	100.	99.9 ± 0.1	99.3 ± 0.2	$77. \pm 2$	$84. \pm 2.$

Ionising radiation tolerance:

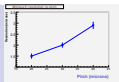
- * **Pixels modified against hole accumulations (thick oxide) and leakage current increase (guard ring)**
- * **MIMOSA-15 tested with $\sim 5 \text{ GeV } e^-$ at DESY after 1 MRad (10 keV X-Ray) exposure : Preliminary results**

- $T = -20^\circ\text{C}$, $t_{r.o.} \sim 180 \mu\text{s}$
- $t_{r.o.} \ll 1\text{ms}$ crucial at T_{room}

Integ. Dose	Noise	S/N (MPV)	Detection Efficiency
0	9.0 ± 1.1	27.8 ± 0.5	100 %
1 MRad	10.7 ± 0.9	19.5 ± 0.2	$99.96 \pm 0.04 \%$

Provisional conclusion:

- * **at least 3 years of running viable at T_{room} (or close to), more if $T \lesssim 0^\circ\text{C}$**
- * **further assessment needed (also with $\sim 10 \text{ MeV } e^-$) : sensors with integ. CDS, ADC,**



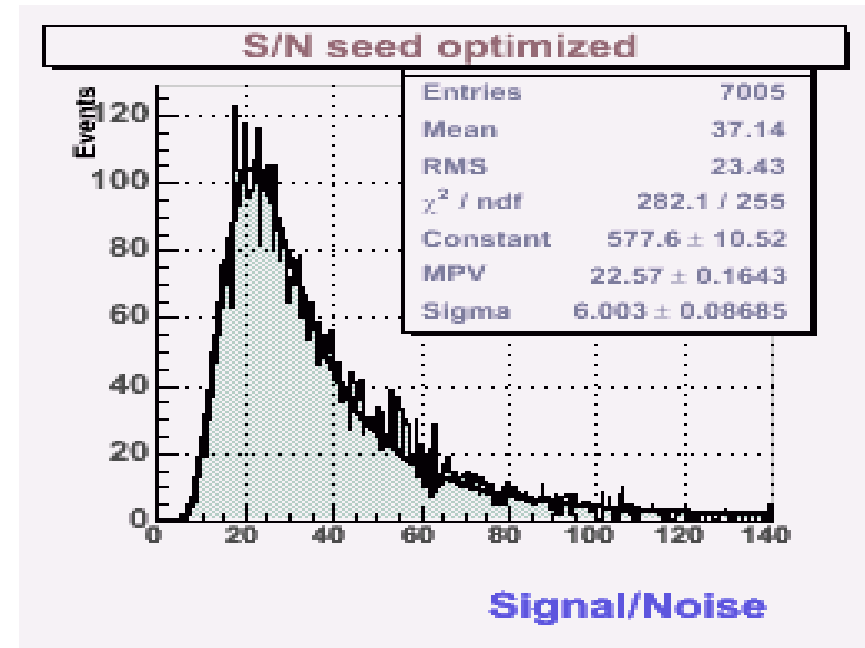
Investigation of sensitivity to ~ 10 MeV electrons (NIEL factor $\sim 1/30$)

\rightarrow similar to beamstrahlung e^\pm in 4 T field at 15 mm radius

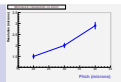
1) MIMOSA-9 exposed to $10^{13} e^-_{9.4\text{MeV}}/\text{cm}^2$ in Darmstadt :
equivalent to $\lesssim 300$ kRad/cm² and $\sim 3 \cdot 10^{11} n_{eq}/\text{cm}^2$

2) Irradiated chip tested with ~ 6 GeV e^- at DESY

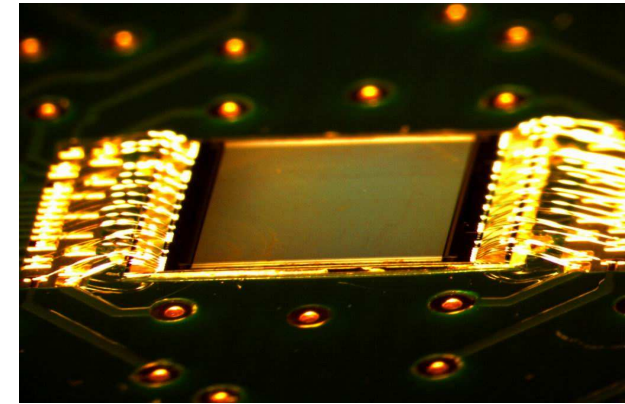
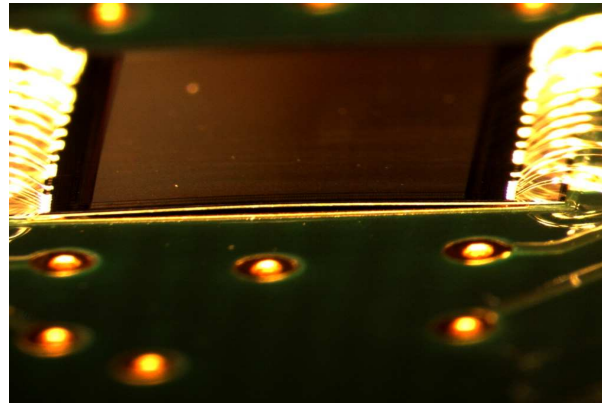
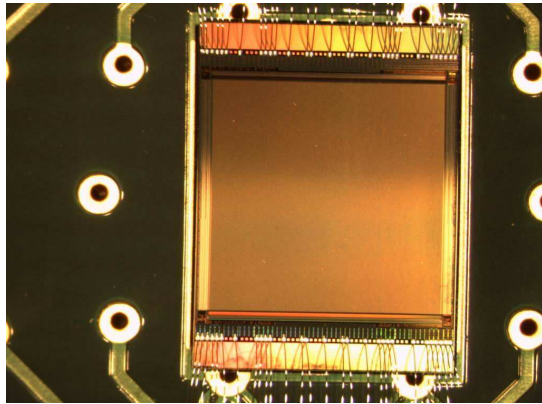
\rightarrow Test result at -20°C : S/N $\sim 23 \rightarrow \epsilon_{det} > 99.3\%$
(before irradiation: S/N ~ 28 and $\epsilon_{det} = 99.93 \pm 0.03\%$)



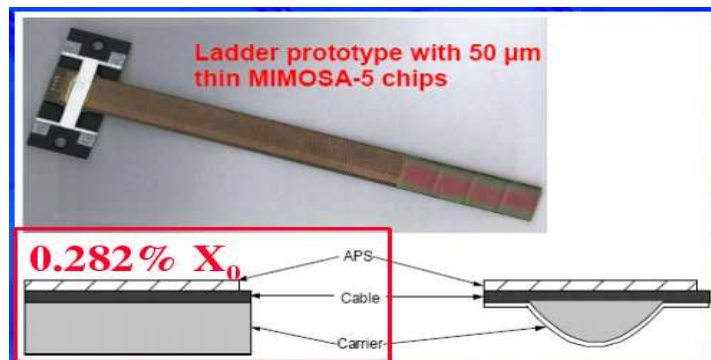
▷ Sensors may need to be also evaluated at room temperature (compatible with very light cooling system)



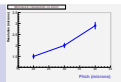
- Industrial thinning (via STAR coll. at LBL) \rightarrow MIMOSA-18 ($5.5 \times 5.5 \text{ mm}^2$ thinned to $50 \mu\text{m}$)



- Devt of ladder equipped with MIMOSA chips (coll. with LBL): STAR ladder ($\lesssim 0.3\% X_0$) \rightarrow ILC ($< 0.2\% X_0$)

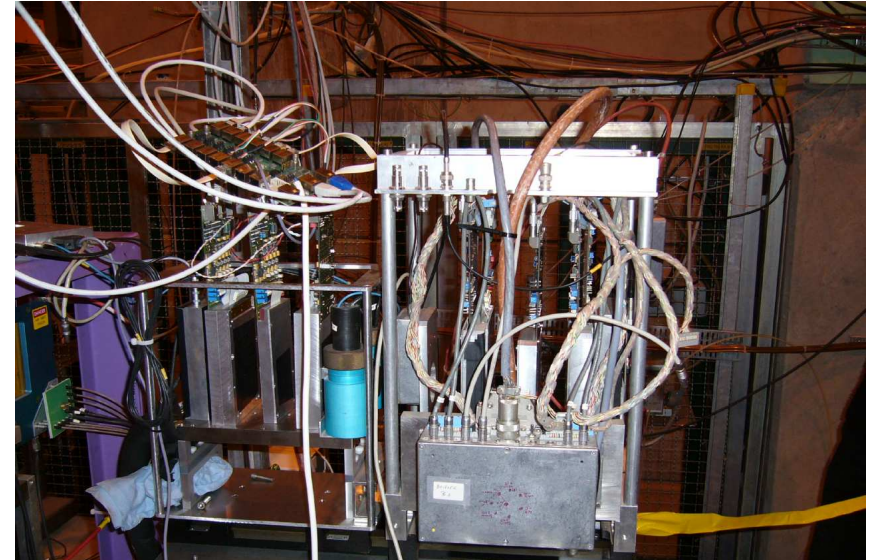


- High precision packaging technologies : \rightarrow mount & connect $\lesssim 5$ MIMOSA-18, thinned to $50 \mu\text{m}$, on support made of industrial diamond, thinned to $50\text{--}100 \mu\text{m}$ and aluminised \equiv mecha. support & heat extractor & cable \rightarrow project started in 2007: diamond ($50\text{--}100 \mu\text{m}$) fabricated \rightarrow assembly of MIMOSA-18 sensors under way



Pixel telescope of IPHC (T.A.P.I.):

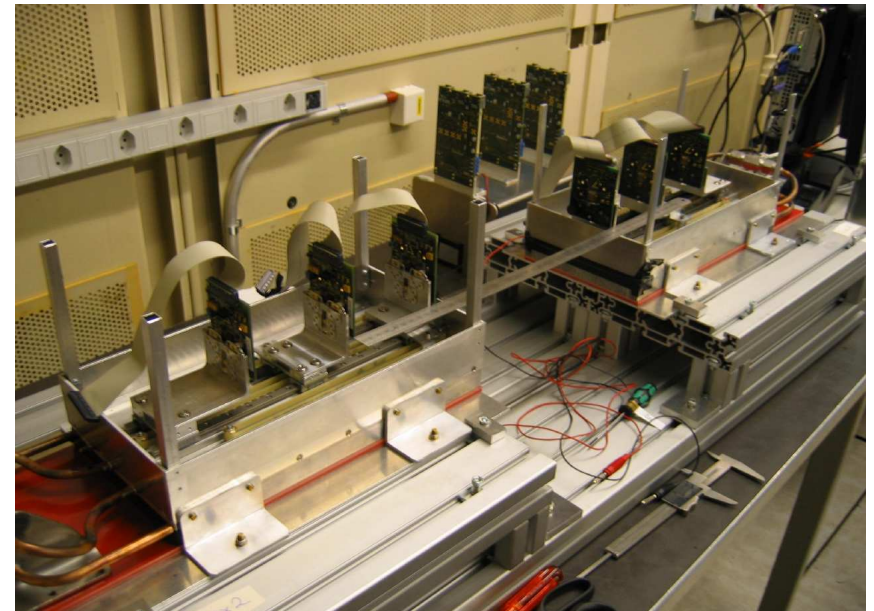
- ≤ 4 MIMOSA-17 and/or -18 sensors
- commissioned in June 2007 at DESY
- data taking campaign in Sept. & Nov. '07 at CERN-SPS
- read-out freq. ~ 10 (M-18) or 25 frames/s (M-17)
- installed in front of standard Si-strip telescope ▷▷▷▷▷

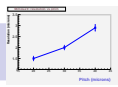


STAR(RHIC) : telescope (3 MIMO-14) inside exp. apparatus (2007) \rightarrow BG meast, no pick-up !

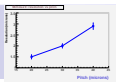
Beam telescope of the FP6 project EUDET

- 2 arms of 3 planes (plus 1 high resolution plane)
- $\sigma_{extrapol.} \lesssim 1 \mu m$ with e^- (3 GeV, DESY)
- 2 steps :
 - ◇ 2007: sensors with analog output
 - \hookrightarrow operationnal facility (< 1 kframe/s)
 - ◇ end 2008: sensor with digital output and integrated \emptyset
 - \hookrightarrow read-out time $\sim 100 \mu s$





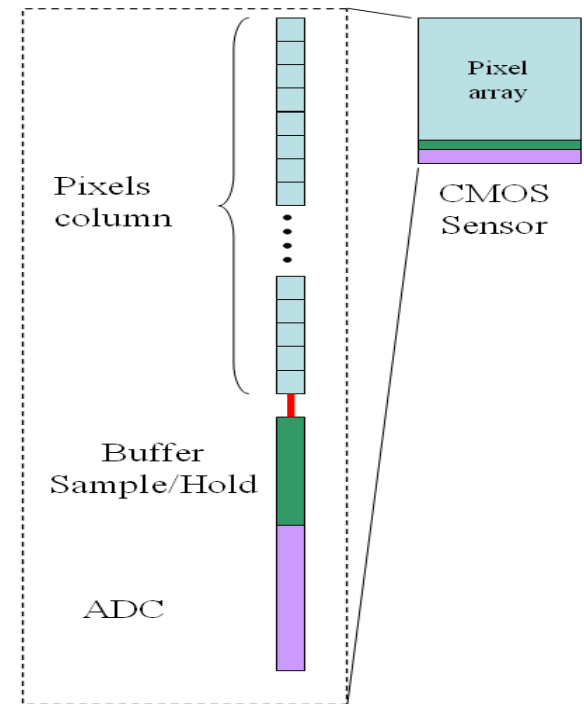
Achieved Performances and Present R&D with Digital Output Sensors

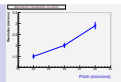


- **Parallel development of 3 components (analog, mixed, digital):**
 - ⊖ column // arrays with CDS/pixel & discriminated outputs
 - ⊖ 4-5 bit ADCs intended to replace discriminators
 - ⊖ \emptyset μ circuits & output memories

- **2 stage approach :**
 - 1) **Develop sensors for mid-term (2009) applications**
 - ↪ less severe requirements, almost suited to 3 outer layers:
 - ◇ EUDET: $1 \times 2 \text{ cm}^2$, $t_{r.o.} \sim 100 \mu\text{s}$, discri. binary charge encoding (no ADC);
 - ◇ STAR: $2 \times 2 \text{ cm}^2$, $t_{r.o.} \sim 200 \mu\text{s}$, discri. binary charge encoding (no ADC);
 - ↪ will be operated in real experimental conditions by 2009/2010

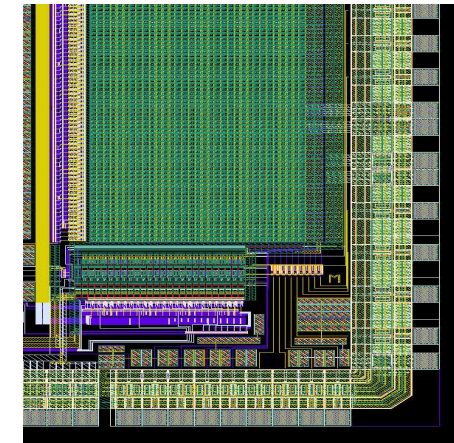
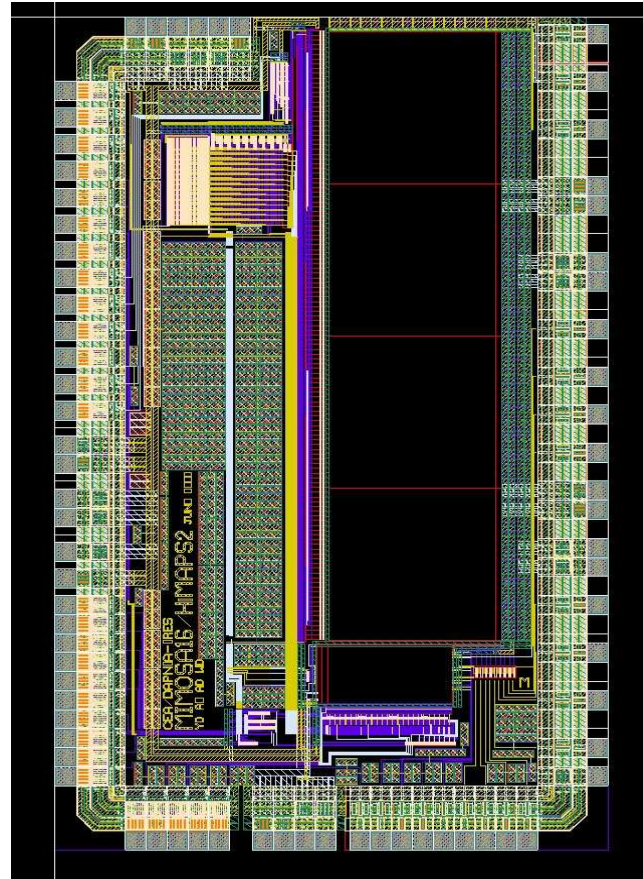
 - 2) **Develop ILC sensors (mainly for inner layers) extrapolating from EUDET & STAR:**
 - ◇ increase row read-out frequency by $\sim 50 \%$
 - ◇ replace discriminators with ADCs





MIMOSA-16 design features :

- AMS-0.35 OPTO translation of MIMOSA-8
 - ↳ $\sim 11\text{--}15 \mu\text{m}$ epitaxy instead of $\lesssim 7 \mu\text{m}$
- 32 // columns of 128 pixels (pitch: $25 \mu\text{m}$)
- on-pixel CDS (DS at end of each column)
- 24 columns ended with discriminator
- 4 sub-arrays :
 - S1** : like MIMOSA-8 ($1.7 \times 1.7 \mu\text{m}^2$ diode)
 - S2** : like MIMOSA-8 ($2.4 \times 2.4 \mu\text{m}^2$ diode)
 - S3** : S2 with ionising radiation tol. pixels
 - S4** : with enhanced in-pixel amplification
(against noise of read-out chain)

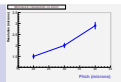


Tests of analog part ("20" & "14" μm epitaxy) :

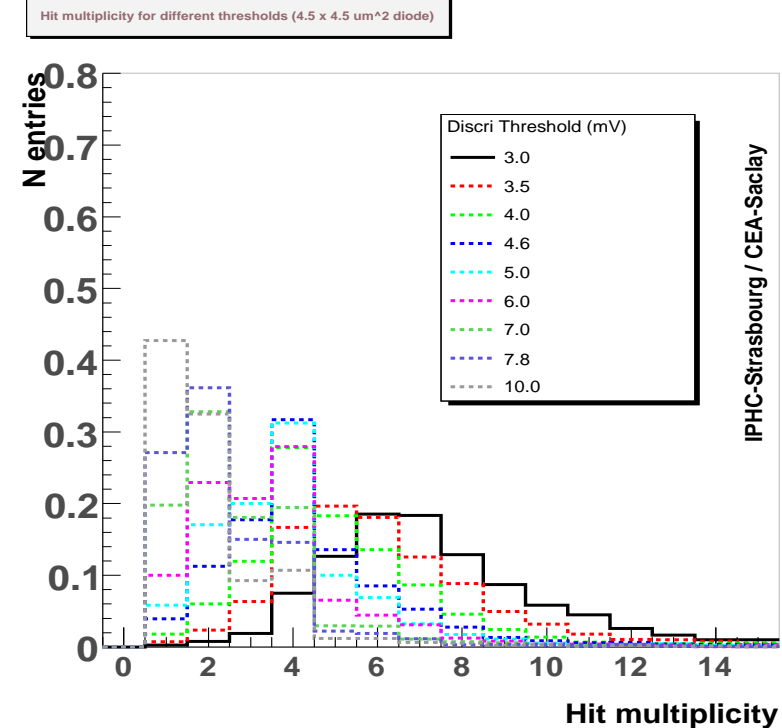
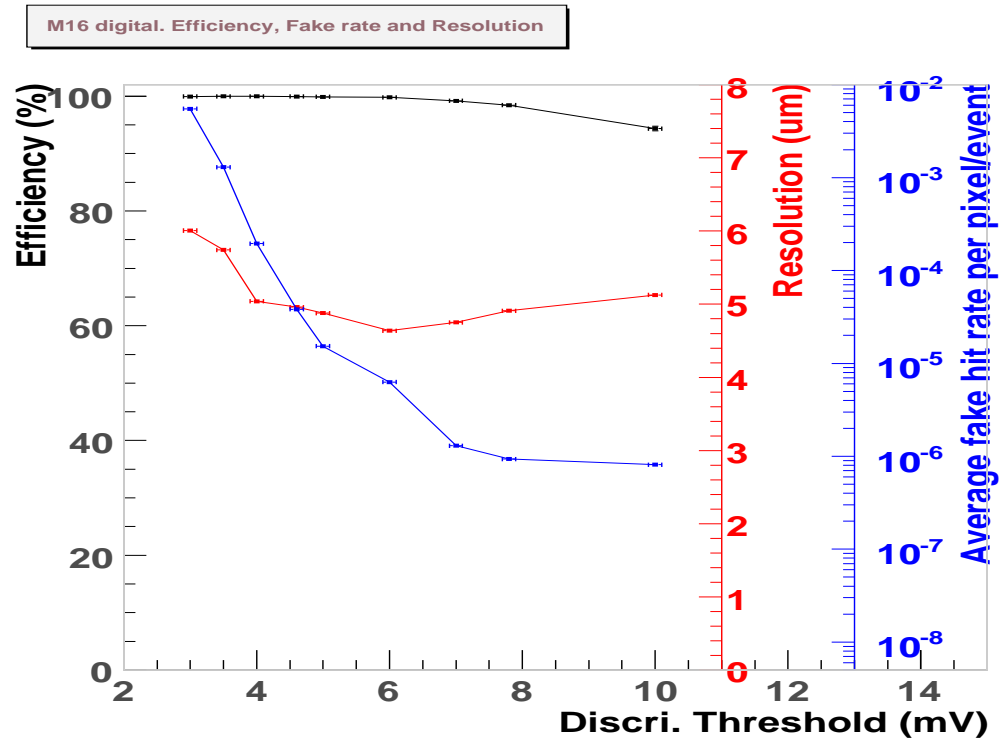
- sensors illuminated with ^{55}Fe source and $F_{r.o.}$ varied up to $\gtrsim 150 \text{ MHz}$
- measurements of N(pixel), FPN (end of column), pedestal variation, CCE (3x3 pixel clusters) vs $F_{r.o.}$

M.i.p. detection with Si-stip telescope studied at CERN in Sept. '07 \rightarrow characterisation of digital response :

- π^- beam of $\sim 180 \text{ GeV}/c$
- measurements of SNR, det. efficiency, fake rate, cluster characteristics, spatial resolution vs discri. threshold

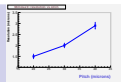


- CERN-SPS ($\sim 180 \text{ GeV } \pi^-$) \rightarrow results of S4 (" $14 \mu\text{m}$ " epitaxy)
- Read-out time $\sim 50 \mu\text{s}$ ($\sim 1/4$ of max. freq. due to DAS limitations)



- Pixel architecture validated for next steps : S4 (SNR ~ 16)

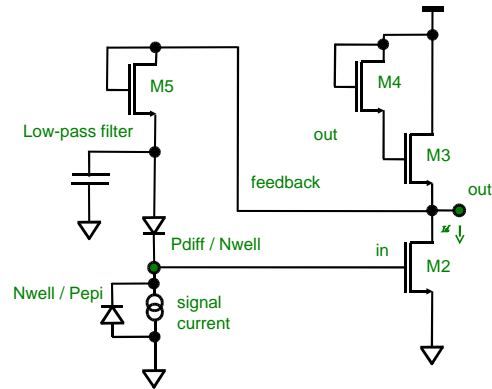
Discr. Threshold	det. efficiency	fake rate	sgle pt resolution
4 m V	99.96 ± 0.03 (stat) %	$\sim 2 \cdot 10^{-4}$	$\sim 4.8\text{--}5.0 \mu\text{m}$
6 m V	99.88 ± 0.05 (stat) %	$< 10^{-5}$	$\sim 4.6 \mu\text{m}$



Best performing pixels (rad. tol. design) :

✧ *self-biased feedback diode (improved gain)*

Amplifier schematics (3): improved common source + continuously biased from feedback (self-biased)

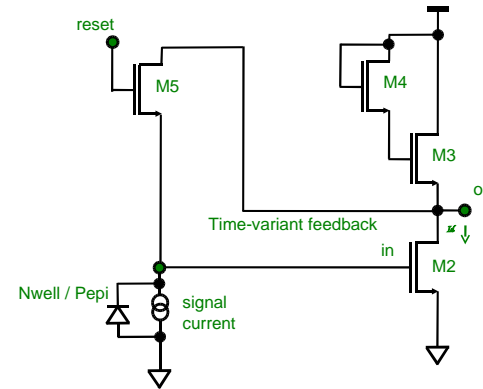


France

A. Dorokhov, IPHC, Strasbourg,

✧ *reset diode (improved gain)*

Amplifier schematics (4): improved common source + reset from feedback (time-variant feedback)



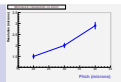
France

A. Dorokhov, IPHC, Strasbourg,

Main results obtained with exposure to ^{55}Fe source :

✧ *Chip-4; $F_{r.o.} = 100 \text{ MHz}$ ($t_{r.o.} = 92.5 \mu\text{s}$); $T \simeq 15^\circ \text{C}$ (coolant) / 20°C (chip);*

Pixel	diode	Noise (ENC)	CCE (4 pix)	CCE (9 pix)	CEE (25 pix)	comment
S6	$14.6 \mu\text{m}^2$	$12.4 e^-$	57 %	73 %	84 %	rad.tol. – self-bias – high gain
S7	$14.6 \mu\text{m}^2$	$11.4 e^-$	58 %	75 %	85 %	stand. – self-bias – high gain
S8	$19.4 \mu\text{m}^2$	$12.8 e^-$	65 %	82 %	90 %	stand. – self-bias – high gain
S9	$11.6 \mu\text{m}^2$	$10.5 e^-$	54 %	72 %	83 %	stand. – self-bias – high gain
S10	$15.2 \mu\text{m}^2$	$13.3 e^-$	60 %	77 %	86 %	rad.tol. – feedback reset – high gain
S12	$15.2 \mu\text{m}^2$	$11.8 e^-$	58 %	75 %	84 %	stand. – feedback reset – high gain



■ Dispersion between chips (rad. tol. pixels, with high gain) :

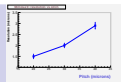
<i>Pixel</i>	<i>chip</i>	<i>Noise (ENC)</i>	<i>CCE (4 pix)</i>	<i>CCE (9 pix)</i>	<i>CEE (25 pix)</i>
S6	4	12.4 e ⁻	57 %	73 %	84 %
	3	12.7 e ⁻	59 %	76 %	86 %
	1	12.6 e ⁻	58 %	74 %	85 %
S10	4	13.3 e ⁻	60 %	77 %	86 %
	3	12.8 e ⁻	58 %	75 %	85 %
	1	13.5 e ⁻	59 %	76 %	86 %

■ Sensitivity to operating temperature (rad. tol. pixels, with high gain) :

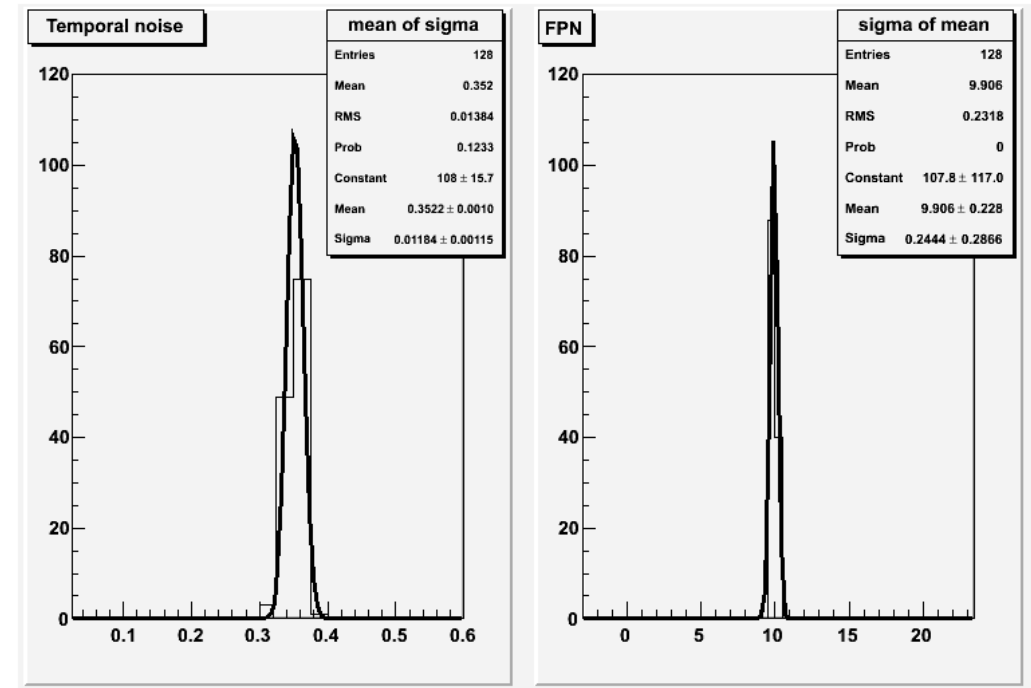
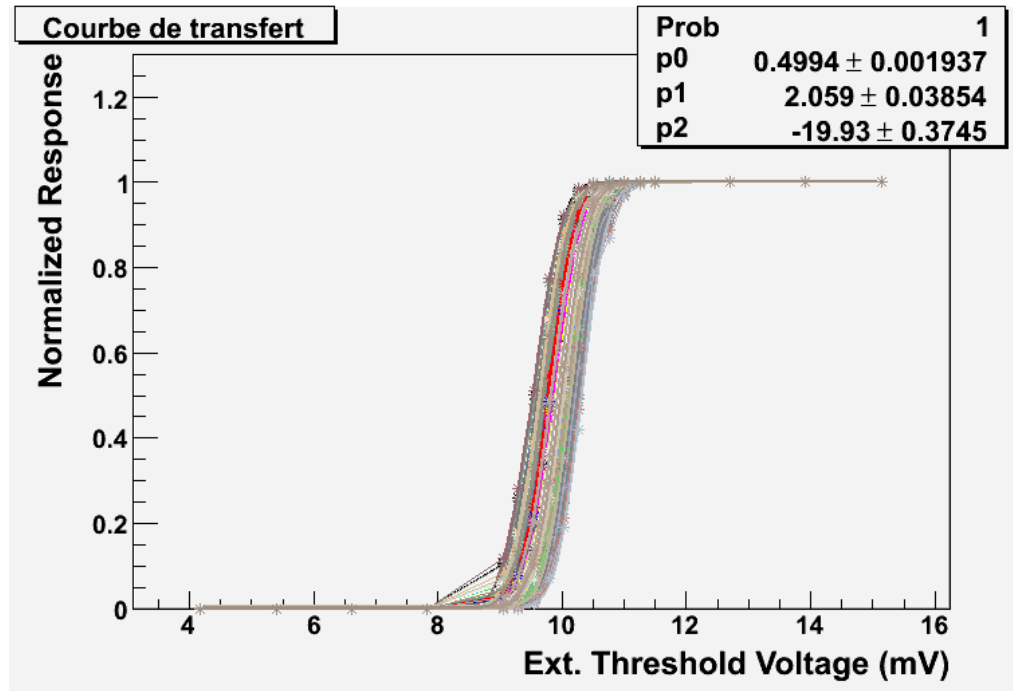
<i>Pixel</i>	<i>T (°C)</i>	<i>Noise (ENC)</i>	<i>CCE (4 pix)</i>	<i>CCE (9 pix)</i>	<i>CEE (25 pix)</i>
S6	0 / 10	12.5 e ⁻	58 %	75 %	85 %
	10 / 15	12.6 e ⁻	58 %	74%	85%
	30 / 35	13.0 e ⁻	59 %	76 %	80 %
S10	0 / 10	12.8 e ⁻	59 %	77 %	84 %
	10 / 15	13.5 e ⁻	59 %	76 %	86 %
	30 / 35	14.2 e ⁻	60 %	76 %	86 %

■ Conclusions :

- ✧ *Pixel array operationnal at nominal frequency and room temperature*
- ✧ *Rad. tol. pixel exhibits rather moderate noise (12.5–13.5 e⁻ ENC), ~ +1 e⁻ ENC w.r.t. standard diode*
- ✧ *Self-bias pixel seems slightly less noisy than reset pixel → assess ionising rad. tol. before chosing*



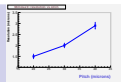
■ Uniform voltage (0 \rightarrow 10 mV) injected in discri. \rightarrow transfer functions of all 128 discriminators :



■ Noise performances for $F_{clock} = 100$ MHz, $T \sim 15 / 20^\circ\text{C}$

* *Temporal noise* $\simeq 0.35$ mV ✓

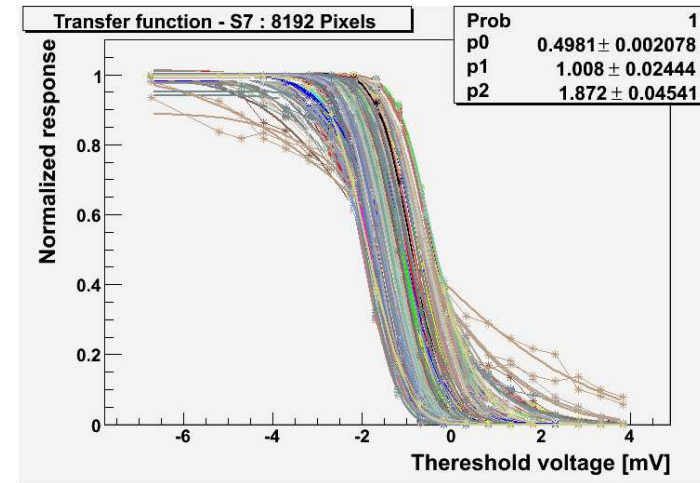
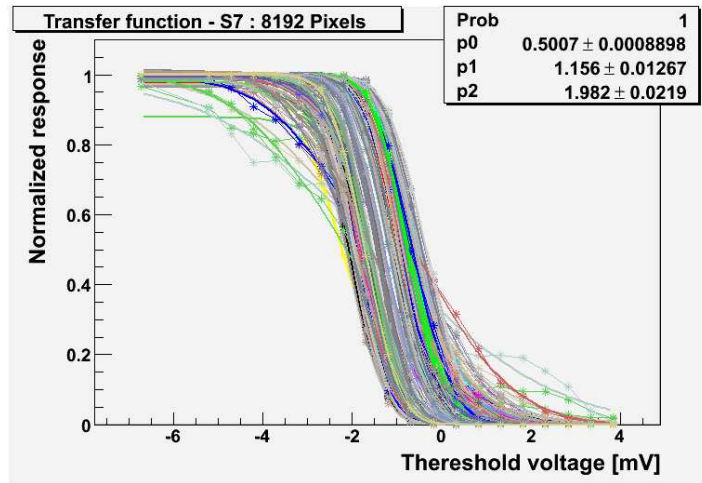
* *Fixed Pattern Noise* $\simeq 0.25$ mV ✓



Threshold scan of pixel noise from S6 & S7 (self-biased feedback with high gain) :

✧ *rad. tol. diode (S6)*

✧ *standard diode (S7)*



Noise derived from scan of S6 (CVC $\simeq 50 \mu V/e^-$) :

✧ *Running conditions : 100 MHz, $T \sim 25^\circ C$*

✧ *Pixel noise $\simeq 0.6 mV$ ✓*

✧ *Fixed Pattern Noise $\simeq 0.3 mV$ (\equiv MIMOSA-16) ✓*

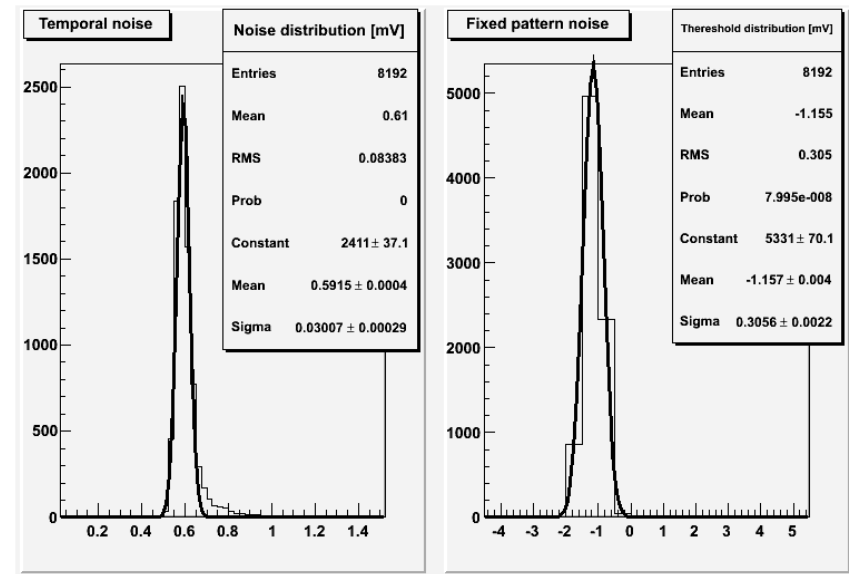
⇒ **Requirements satisfied**

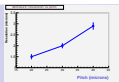
Next steps:

✧ *complete lab tests*

✧ *check radiation tol.*

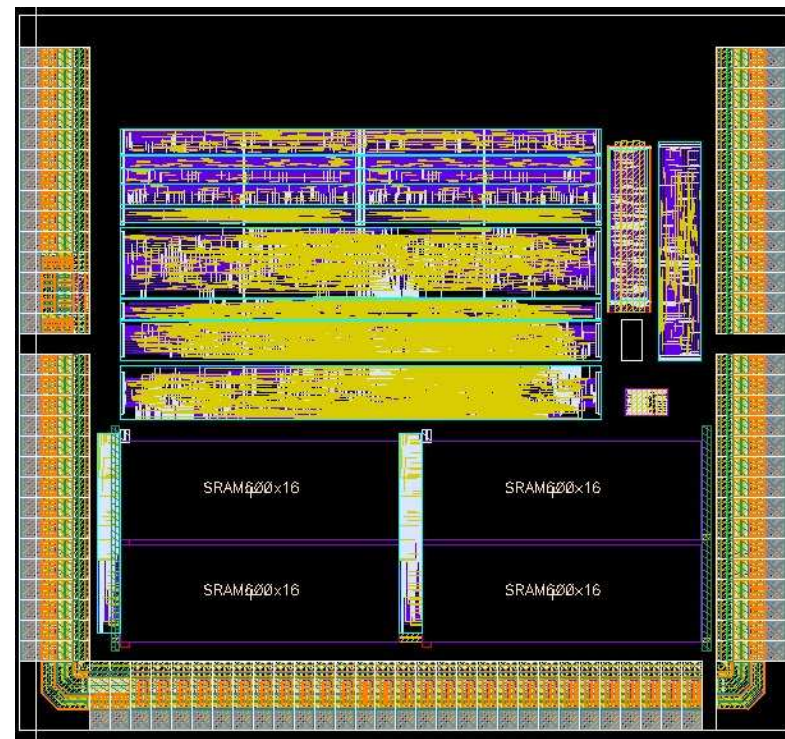
✧ *check m.i.p. detection perfo. (SPS in August)*





■ 1st chip (SUZE-01) with integrated \emptyset and output memories (no pixels) :

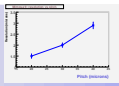
- ✧ 2 step, raw by raw, logic :
 - ◇ step-1 (inside blocks of 64 columns) :
 - identify up to 6 series of ≤ 4 neighbour pixels per raw
 - delivering signal $>$ discriminator threshold
 - ◇ step-2 : read-out outcome of step-1 in all blocks
 - and keep up to 9 series of ≤ 4 neighbour pixels
- ✧ 4 output memories (512x16 bits) taken from AMS I.P. lib.
- ✧ surface $\sim 3.9 \times 3.6 \text{ mm}^2$



■ Test results summary :

- ✧ back from foundry end of Sept. '07 \rightarrow (lab) tests completed
- ✧ design performances reproduced up to $1.15 \times$ design read-out frequency (T_{room}) :
 - ▷ noise values as predicted, no pattern encoding error

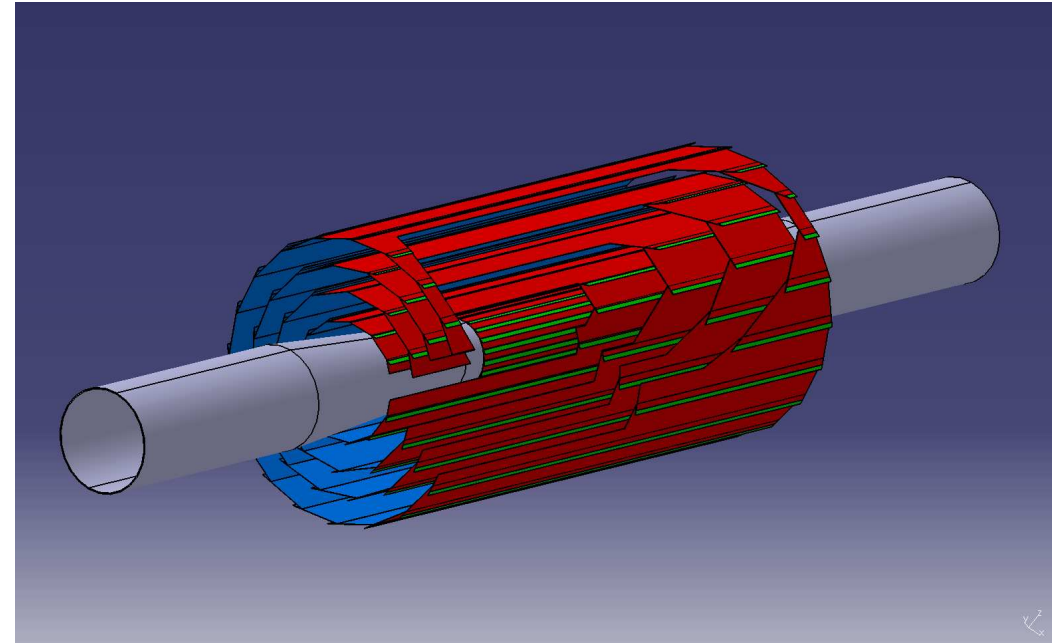
■ Still to do : evaluate radiation tolerance of ouput memories



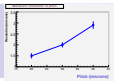
Example of Basic Vertex Detector Design features

- *ILD geometry: ≥ 5 cylind. layers ($R = 15\text{--}60$ mm), $\|\cos\theta\| \leq 0.90 - 0.97$*
- *L0 and L1 : optimised against occupancy* ■ *L2, L3 and L4 : optimised against power dissipation*
- *Pixel pitch varied from ~ 20 μm (L0–L1) to $\gtrsim 30$ μm (L2–L4) \rightarrow minimise P_{diss}*

Layer	Radius (mm)	Pitch (μm)	$t_{r.o.}$ (μs)	N_{lad}	N_{pix} (10^6)	P_{diss}^{inst} (W)	P_{diss}^{mean} (W)
L0	15	20	25	20	25	<100	<5
L1	≤ 25	25	50	≤ 26	≤ 65	<130	<7
L2	37	33	~ 100	24	50	<90	<5
L3	48	33	~ 100	32	80	<120	<6
L4	60	33	~ 100	40	150	<125	<8
Total				142	330	<600	3–30



- *Ultra thin layers: $\lesssim 0.2$ % X_0/layer (extrapolated from STAR-HFT; $\lesssim 40$ μm thin sensors)*
- *Very low P_{diss}^{mean} : $\ll 100$ W (exact value depends on duty cycle)*
- *Fake hit rate $\lesssim 10^{-5}$ \rightarrow whole detector \cong close to 1 GB/s (mainly from e_{BS}^{\pm})*



■ 1st generation of CMOS sensors with digital (binary) output almost completed :

- ⌞ *performances suited to ILC-VD outer layers*
- ⌞ *equip EUDET beam telescope in 2009 (binary with \emptyset)*
- ⌞ *equip 3 sectors of STAR-HFT in 2009 (binary without \emptyset) \rightsquigarrow D^0 physics in 2010*

■ 2nd generation (faster, integrated ADCs) :

- ⌞ *aim for performances suited for the ILC-VD inner layers*
- ⌞ *1st (small) pixel matrix with integrated ADCs to be fabricated in 2008*
 - \Rightarrow *1st real scale prototype in 2010 ?*
- ⌞ *in parallel : explore alternatives to AMS-0.35 Opto : 0.18 Opto ?, customised substrate, 3DIT*

■ System integration :

- ⌞ *50 μ m thinning \sim under control*
- ⌞ *edgeless dicing under study*
- ⌞ *1st prototype ladder (extrapolated from STAR-HFT) in 2010/11 ?*